ECE 230L

INTRODUCTION TO MICROELECTRONIC DEVICES AND CIRCUITS

Review of

SEMICONDUCTOR DEVICES

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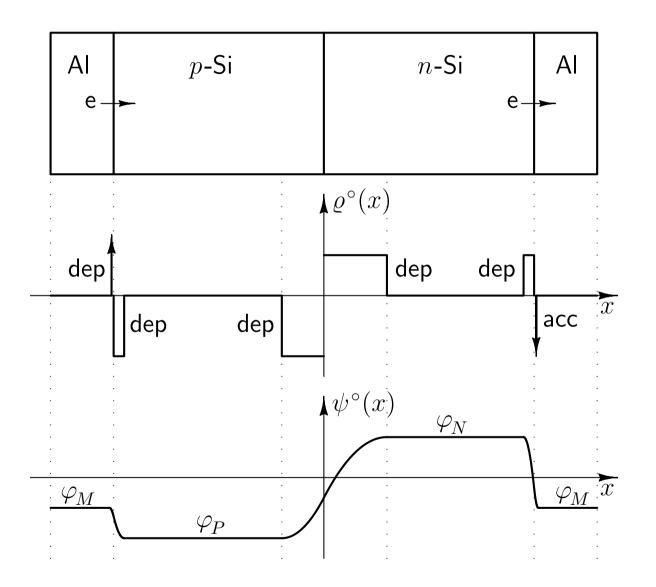
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FORMATION OF THE DEPLETION REGION IN PN-JUNCTION DIODES

- The depletion region is formed because holes from the p-side diffuse to the n-side where they recombine with electrons, and electrons from the n-side diffuse to the p-side where they recombine with holes.
- ullet The concentrations of electrons and holes in the depletion region are much smaller than N_a in the p-side and N_d in the n-side.
- In the depletion region, there is a built-in electric field and non-zero carrier-concentration gradients:
 - \circ Hole diffusion \to is cancelled by hole drift \leftarrow , and
 - \circ Electron diffusion \leftarrow is cancelled by electron drift \rightarrow .
- The net recombination or generation rate distributions are zero the depletion region and the quasi neutral regions.
- Charge conservation requires that

$$N_a^- W_{d,P}^{\circ} = N_d^+ W_{d,N}^{\circ}$$
.

PN-JUNCTION DIODE AT THERMAL EQUILIBRIUM



PN-JUNCTION DIODE AT THERMAL EQUILIBRIUM

ullet The built-in potential V_{bi} is given by

$$V_{bi} = \frac{k_B T}{q} \ln \left(\frac{N_a^- N_d^+}{n_i^2} \right) .$$

ullet The depletion-region width W_d° at thermal equilibrium is given by

$$W_d^{\circ} = \sqrt{\frac{2 \epsilon_{Si}}{q} \cdot \frac{(N_a^- + N_d^+)}{N_a^- N_d^+} V_{bi}} .$$

PN-JUNCTION DIODE AT THERMAL EQUILIBRIUM

ullet The p-side depletion-region width $W_{d,P}^{\circ}$ at thermal equilibrium is

$$W_{d,P}^{\circ} = \frac{N_d^+}{\left(N_a^- + N_d^+\right)} W_d^{\circ} = \sqrt{\frac{2 \epsilon_{Si}}{q} \cdot \frac{N_d^+}{N_a^- \left(N_a^- + N_d^+\right)}} V_{bi} .$$

ullet The n-side depletion-region width $W_{d,N}^\circ$ at thermal equilibrium is

$$W_{d,N}^{\circ} = \frac{N_a^-}{\left(N_a^- + N_d^+\right)} W_d^{\circ} = \sqrt{\frac{2 \epsilon_{Si}}{q} \cdot \frac{N_a^-}{N_d^+ \left(N_a^- + N_d^+\right)}} V_{bi} .$$

• For $V_{PN} > 0$:

- $\circ W_d(V_{PN}) \downarrow$,
- \circ The barrier becomes $\left(V_{bi}-V_{PN}
 ight)\downarrow$,
- \circ The magnitude of the field in the depletion region \downarrow , and
- \circ The depletion-region carrier gradients $dp/dx \uparrow$ and $dn/dx \uparrow$.

• For $V_{PN} < 0$:

- $\circ W_d(V_{PN}) \uparrow$,
- \circ The barrier becomes $(V_{bi}-V_{PN})\uparrow$,
- The magnitude of the field in the depletion region ↑, and
- \circ The depletion-region carrier gradients $dp/dx \downarrow$ and $dn/dx \downarrow$.

ullet The width of the depletion region $W_d\left(V_{PN}\right)$ is given by

$$W_d(V_{PN}) = \sqrt{\frac{2 \epsilon_{Si}}{q} \cdot \frac{(N_a^- + N_d^+)}{N_a^- N_d^+} (V_{bi} - V_{PN})}.$$

• The p-side depletion-region width is

$$W_{d,P}(V_{PN}) = \sqrt{\frac{2 \epsilon_{Si}}{q} \cdot \frac{N_d^+}{N_a^- (N_a^- + N_d^+)} (V_{bi} - V_{PN})}.$$

• The n-side depletion-region width is

$$W_{d,N}(V_{PN}) = \sqrt{\frac{2 \epsilon_{Si}}{q} \cdot \frac{N_a^-}{N_d^+ (N_a^- + N_d^+)} (V_{bi} - V_{PN})}.$$

• The field at x = 0 is given by

$$\mathcal{E}_{x \cdot max}(V_{PN}) \equiv \mathcal{E}_{x}(0, V_{PN}),$$

$$= -\frac{q N_{a}^{-} W_{d,P}(V_{PN})}{\epsilon_{Si}} = -\frac{q N_{d}^{+} W_{d,N}(V_{PN})}{\epsilon_{Si}},$$

$$= -\sqrt{\frac{2 q}{\epsilon_{Si}} \cdot \frac{N_{a}^{-} N_{d}^{+}}{(N_{a}^{-} + N_{d}^{+})} (V_{bi} - V_{PN})}.$$

 The minority-carrier concentrations at the depletion-region edges under bias conditions are given by

$$p_N(W_{d,N},V_{PN}) = p_N^{\circ} \exp\left(\frac{q V_{PN}}{k_B T}\right) ,$$

and

$$n_P(-W_{d,P},V_{PN}) = n_P^\circ \exp\left(\frac{q V_{PN}}{k_B T}\right)$$
.

These important relationships are called the law of the junction.

- Under forward-bias static conditions, holes are transported in the positive x direction by drift and diffusion in the p-side quasi-neutral region where they also recombine with electrons injected from the n-side of the junction.
- Holes and electrons recombine throughout the depletion region. Under the assumption of a uniform net recombination rate throughout this region, the hole current density decreases linearly from the p-side depletion-region edge to the n-side depletion-region edge.
- Holes are transported in the positive x direction mainly by diffusion in the n-side quasi-neutral region where they also recombine with the majority electrons.

- Under forward-bias static conditions, electrons are transported in the negative x direction by drift and diffusion in the n-side quasi-neutral region where they also recombine with holes injected from the p-side of the junction.
- Electrons and holes recombine throughout the depletion region. Under the assumption of a uniform net recombination rate throughout this region, the electron current density decreases linearly from the n-side depletion-region edge to the p-side depletion-region edge.
- Electrons are transported in the negative x direction mainly by diffusion in the p-side quasi-neutral region where they also recombine with the majority holes.

The PN-junction diode current density is then given by

$$J_D(V_{PN}) = J_{S \cdot diff} \, \left[\exp \left(\frac{q \, V_{PN}}{k_B T} \right) - 1 \, \right] + J_{S \cdot scr}(V_{PN}) \, \left[\exp \left(\frac{q \, V_{PN}}{2 \, k_B T} \right) - 1 \, \right] \, , \label{eq:JD}$$

where

$$J_{S \cdot diff} = \frac{q D_{n,P} n_i^2}{L_{n,P} N_a^-} + \frac{q D_{p,N} n_i^2}{L_{p,N} N_d^+},$$

$$J_{S \cdot scr}(V_{PN}) = \frac{q \, n_i \, W_d(V_{PN})}{2 \, \tau_{rec,SCR}},$$

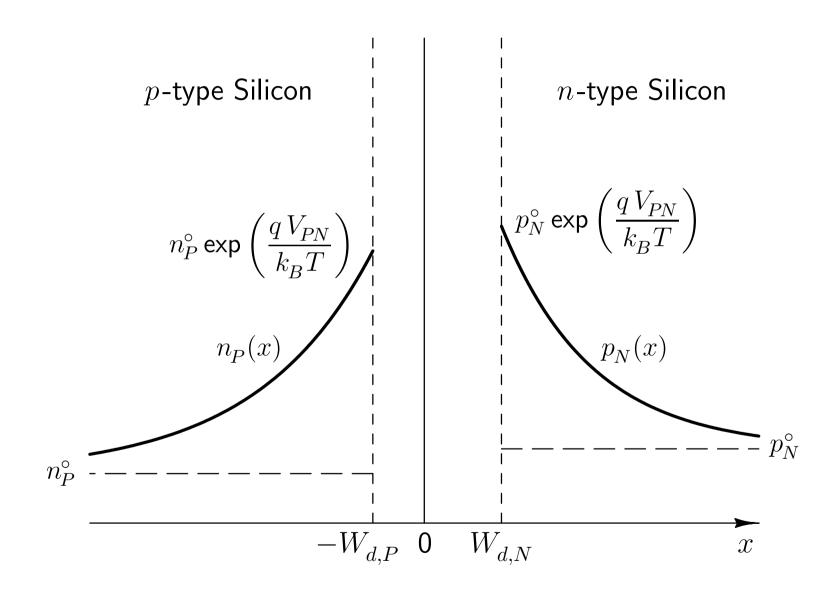
and

$$au_{rec,SCR} pprox rac{ au_{rec,P} + au_{rec,N}}{2}$$
 .

• The PN-junction diode current $I_D(V_{PN})$ is then given by

$$\begin{split} I_D(V_{PN}) &= A_d \, J_D(V_{PN}) \,, \\ &= I_{S \cdot diff} \left[\exp \left(\frac{q \, V_{PN}}{k_B T} \right) - 1 \, \right] + I_{S \cdot scr}(V_{PN}) \, \left[\exp \left(\frac{q \, V_{PN}}{2 \, k_B T} \right) - 1 \, \right] \,, \end{split}$$

where A_d is the diode area.



ullet When the applied bias voltage V_{PN} is negative, the PN-junction diode is reverse-biased. Under such conditions

$$\circ W_d(V_{PN}) \uparrow$$
,

- \circ $|\mathcal{E}_x| \uparrow$ in the depletion region,
- $\circ \ (V_{bi} V_{PN}) \uparrow$ across the junction because $V_{PN} < 0$,
- $\circ \ p_N(W_{d,N}) \downarrow < p_N^\circ$ because $V_{PN} <$ 0 and $\exp(q V_{PN}/k_B T) <$ 1,
- \circ Holes in the n-side quasi-neutral region diffuse towards the junction,
- $\circ \ n_P(-W_{d,P}) \downarrow < n_P^\circ \ \text{because} \ V_{PN} < 0 \ \text{and} \ \exp(q \, V_{PN}/k_B T) < 1 \text{,}$
- \circ Electrons in the p-side quasi-neutral region diffuse towards the junction, and
- There is net electron-hole-pair generation throughout the diode.

The minority-carrier lifetimes and diffusion lengths used in calculating the carrier-concentration distributions are minority-carrier generation lifetimes and diffusion lengths. In other words:

$$\begin{split} \tau_{rec \cdot p,N} & \longrightarrow & \tau_{gen \cdot p,N} \,, \\ L_{p,N} &= \sqrt{\tau_{rec \cdot p,N} \, D_{p,N}} & \longrightarrow & L_{p,N} &= \sqrt{\tau_{gen \cdot p,N} \, D_{p,N}} \,, \\ \tau_{rec \cdot n,P} & \longrightarrow & \tau_{gen \cdot n,P} \,, \\ L_{n,P} &= \sqrt{\tau_{rec \cdot n,P} \, D_{n,P}} & \longrightarrow & L_{n,P} &= \sqrt{\tau_{gen \cdot n,P} \, D_{n,P}} \,, \\ \tau_{rec,SCR} & \longrightarrow & \tau_{gen,SCR} \,. \end{split}$$

- Holes generated in the n-side quasi-neutral region diffuse towards the depletion region where they join holes generated there. These holes are swept by the electric field in the depletion region towards the p-side depletion-region edge. More holes are generated in the p-side quasi-neutral region, and all holes are transported there by drift and diffusion towards the metal contact at $x=-W_P$, and
- Electrons generated in the p-side quasi-neutral region diffuse towards the depletion region where they join electrons generated there. These electrons are swept by the electric field in the depletion region towards the n-side depletion-region edge. More electrons are generated in the n-side quasi-neutral region, and all electrons are transported there by drift and diffusion towards the metal contact at $x = W_N$.

 Under reverse-bias conditions, the space-charge-generation current density is given by

$$\begin{split} J_{D \cdot scg}(V_{PN}) &= \frac{q \, n_i \, W_d \, (V_{PN})}{2 \, \tau_{gen,SCR}} \, \left[\, \exp \left(\frac{q \, V_{PN}}{2 \, k_B T} \right) - 1 \, \right] \,, \\ &\approx - \, \frac{q \, n_i \, W_d \, (V_{PN})}{2 \, \tau_{gen,SCR}} \qquad \text{for } V_{PN} \leq - \, 6 \, k_B T / q \,\,. \end{split}$$

It is evident that the reverse-bias space-charge-generation current density has a weak bias-voltage dependence.

REVERSE-BIAS BREAKDOWN IN A PN-JUNCTION DIODE

- ullet At large enough reverse-bias voltages, the reverse-bias diode current I_D increases substantially due to avalanche multiplication, a process that results directly from carrier impact ionization.
- Breakdown can also occur due to carrier tunneling at low bias voltages in heavily doped PN-junction diodes. As the dopant concentrations in both sides of a PN-junction diode are increased, the depletion width decreases.
- For depletion widths near 50 Å, carriers can tunnel through the potential barrier between valence and conduction bands. This lower voltage breakdown in heavily doped PN-junction diodes is called **tunneling breakdown** or **Zener breakdown**.

 \bullet The small-signal capacitance per unit area $C_{pn}(V_{PN})$ of a PN-junction diode is given by :

$$\begin{split} C_{pn}(V_{PN}) &\equiv \left| \frac{dQ_{pn}(V_{PN})}{dV_{PN}} \right| , \\ &= \left| \frac{dQ_{pn\cdot dep}(V_{PN})}{dV_{PN}} \right| + \left| \frac{dQ_{pn\cdot diff,P}(V_{PN})}{dV_{PN}} \right| + \left| \frac{dQ_{pn\cdot diff,N}(V_{PN})}{dV_{PN}} \right| , \\ &= C_{pn\cdot dep}(V_{PN}) + C_{pn\cdot diff,P}(V_{PN}) + C_{pn\cdot diff,N}(V_{PN}) . \end{split}$$

 \bullet The small-signal PN-junction diode depletion capacitance $C_{pn\cdot dep}(V_{PN})$ per unit area is given by

$$C_{pn\cdot dep}(V_{PN}) = \sqrt{\frac{q \,\epsilon_{Si}}{2} \cdot \frac{N_a^- N_d^+}{\left(N_a^- + N_d^+\right)} \cdot \frac{1}{\left(V_{bi} - V_{PN}\right)}}$$
.

• The small-signal diffusion capacitance $C_{pn\cdot diff,N}(V_{PN})$ per unit area on the n-side of the junction for a long-base n-side quasi-neutral region is given by

$$C_{pn\cdot diff,N}(V_{PN}) = \frac{q^2 n_i^2 L_{p,N}}{k_B T N_d^+} \exp\left(\frac{q V_{PN}}{k_B T}\right) .$$

• The small-signal diffusion capacitance $C_{pn\cdot diff,P}(V_{PN})$ per unit area on the p-side of the junction for a long-base p-side quasi-neutral region is given by

$$C_{pn\cdot diff,P}(V_{PN}) = \frac{q^2 n_i^2 L_{n,P}}{k_B T N_a^-} \exp\left(\frac{q V_{PN}}{k_B T}\right) .$$

• The PN-junction diffusion capacitance per unit area can be expressed as

$$\begin{split} C_{pn\cdot diff}(V_{PN}) &= \left[\,C_{pn\cdot diff,P}(\mathbf{0}) + C_{pn\cdot diff,N}(\mathbf{0})\,\right] \exp\left(\frac{q\,V_{PN}}{k_BT}\right)\,, \\ &= C_{pn\cdot diff}(\mathbf{0}) \exp\left(\frac{q\,V_{PN}}{k_BT}\right)\,, \end{split}$$

where

$$C_{pn\cdot diff}(0) = C_{pn\cdot diff,P}(0) + C_{pn\cdot diff,N}(0).$$

 The small-signal PN-junction diode capacitance per unit area is given by

$$C_{pn}(V_{PN}) = C_{pn\cdot dep}(\mathbf{0}) \sqrt{\frac{V_{bi}}{\left(V_{bi} - V_{PN}\right)}} \ + C_{pn\cdot diff}(\mathbf{0}) \exp\left(\frac{q\,V_{PN}}{k_B T}\right) \ , \label{eq:cpn}$$

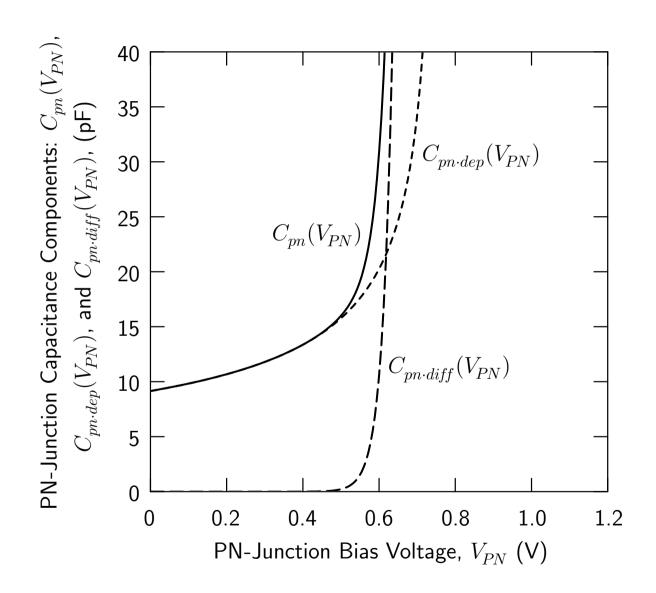
where

$$C_{pn\cdot dep}(0) = \sqrt{\frac{q \,\epsilon_{Si}}{2} \cdot \frac{N_a^- N_d^+}{(N_a^- + N_d^+)} \cdot \frac{1}{V_{bi}}},$$

$$C_{pn\cdot diff,P}(0) = \frac{q^2 n_i^2 L_{n,P}}{k_B T N_a^-},$$

and

$$C_{pn\cdot diff,N}(0) = \frac{q^2 n_i^2 L_{p,N}}{k_B T N_d^+}.$$



MOSCAP PARAMETERS, VARIABLES, AND DISTRIBUTIONS

- \bullet $N_{a.B}^-$ lonized-acceptor concentration in the substrate region,
- X_{ox} Gate-oxide thickness,
- Q_f Fixed-oxide charge density $(Q_f = q N_f)$,
- ullet $Q_{it}(V_{GB})$ Interface-trap charge density $\left(Q_{it}(V_{GB})=q\,N_{it}(V_{GB})\right)$, and
- φ_{PM} Contact-potential difference between the p-type substrate and the backside metal contact.
- ullet $Q_G(V_{GB})$ Charge density in the metal-gate region,
- ullet $\mathcal{E}_{x,OX}(V_{GB})$ Electric field in the x-direction in a charge-free gate-oxide layer,
- ullet $V_{OX}(V_{GB})$ Voltage across the gate-oxide layer,
- ullet $Q_{SC,B}(V_{GB})$ Charge density in the substrate space-charge region, and
- ullet $V_{SCB}(V_{GB})$ Voltage across the substrate space-charge region.

MOSCAP PARAMETERS, VARIABLES, AND DISTRIBUTIONS

 \bullet The charge density $Q_{SC\!,B}(V_{GB})$ (C/cm²) in the substrate space-charge region is defined as

$$Q_{SC,B}(V_{GB}) \equiv \int_{0^+}^{ ext{neutral bulk}} \varrho_B(x, V_{GB}) \ dx$$
 .

BASIC RELATIONSHIPS

The electrostatic-potential-distribution relationship

$$V_{GB} = V_{OX}(V_{GB}) + V_{SC,B}(V_{GB}) + \varphi_{PM},$$

The charge-density-conservation relationship

$$Q_G(V_{GB}) + Q_f + Q_{it}(V_{GB}) + Q_{SC,B}(V_{GB}) = 0.$$

 The electric-displacement-vector continuity at the metal/gate-oxide interface

$$\epsilon_{ox} \mathcal{E}_{x,OX}(V_{GB}) + Q_f + Q_{it}(V_{GB}) = \epsilon_{Si} \mathcal{E}_{x,B}(0^+, V_{GB}),$$
$$= -Q_{SCB}(V_{GB}).$$

The electric-displacement-vector continuity at the gate-oxide/substrate interface

$$Q_G(V_{GB}) = \epsilon_{ox} \, \mathcal{E}_{x,OX}(V_{GB}) \, .$$

BASIC RELATIONSHIPS

ullet The voltage $V_{OX}(V_{GB})$ across a charge-free gate-oxide layer and the electric field $\mathcal{E}_{x,OX}(V_{GB})$ in it are related by :

$$V_{OX}(V_{GB}) = X_{ox} \ \mathcal{E}_{x,OX}(V_{GB}) \,, \quad \text{or} \quad \mathcal{E}_{x,OX}(V_{GB}) = \frac{V_{OX}(V_{GB})}{X_{ox}} \,.$$

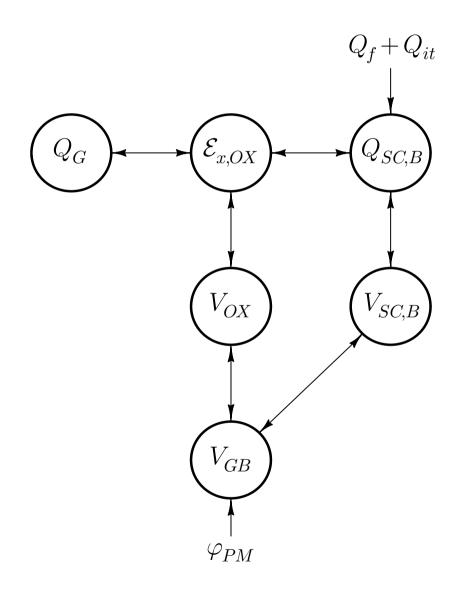
 The electron and hole concentration distributions are related to the electrostatic-potential distribution by

$$n_B(x,V_{GB}) = n_B^\circ \exp\left(\frac{q\left[\psi_B(x,V_{GB}) - \psi_B(\text{neutral bulk})\right]}{k_BT}\right)\,,$$

and

$$p_B(x,V_{GB}) = p_B^\circ \exp\left(-\frac{q\left[\psi_B(x,V_{GB}) - \psi_B(\text{neutral bulk})\right]}{k_BT}\right) \,.$$

BASIC RELATIONSHIPS



MOSCAP AT THERMAL EQUILIBRIUM

 \bullet A metal-gate MOS capacitor is at thermal equilibrium at $V_{GB}=0$. At thermal equilibrium,

$$V_{OX}^{\circ} + V_{SC,B}^{\circ} + \varphi_{PM} = 0.$$

• At thermal equilibrium, the charge-density-conservation relationship at thermal equilibrium is expressed as

$$Q_G^{\circ} + Q_f + Q_{it}^{\circ} + Q_{SC,B}^{\circ} = 0$$
.

• The values of the flat-band and threshold voltages will determine the condition of the substrate space-charge region at thermal equilibrium. The approximate analysis can be then applied to find $V_{SC,B}^{\circ}$ and $Q_{SC,B}^{\circ}$.

MOSCAP AT THERMAL EQUILIBRIUM

ullet The oxide electric field $\mathcal{E}_{x,OX}^{\circ}$ at thermal equilibrium is given by

$$\mathcal{E}_{x,OX}^{\circ} = \frac{Q_G^{\circ}}{\epsilon_{ox}} = -\frac{Q_f + Q_{it}^{\circ} + Q_{SC,B}^{\circ}}{\epsilon_{ox}},$$

and the thermal-equilibrium oxide voltage V_{OX}° is given by

$$V_{OX}^{\circ} = X_{ox} \mathcal{E}_{x,OX}^{\circ},$$

$$= -X_{ox} \frac{Q_f + Q_{it}^{\circ} + Q_{SC,B}^{\circ}}{\epsilon_{ox}},$$

$$= -\frac{Q_f + Q_{it}^{\circ} + Q_{SC,B}^{\circ}}{C_{ox}} = -\left(V_{SC,B}^{\circ} + \varphi_{PM}\right).$$

which can be rearranged to read

$$Q_{SC,B}^{\circ}(V_{SC,B}^{\circ}) = C_{ox} V_{SC,B}^{\circ} + C_{ox} \varphi_{PM} - (Q_f + Q_{it}^{\circ}).$$

The Accumulation Bias Range:

•
$$V_{GB} \leq V_{FB \cdot N}$$
.

$$\bullet \ p_B(\mathbf{0}, V_{GB}) \ge p_B^{\circ}.$$

•
$$n_B(0, V_{GB}) \le n_B^{\circ}$$
.

In the approximate analysis:

•
$$V_{SC,B}^{acc}(V_{GB}) \ll V_{OX}^{acc}(V_{GB}) + \varphi_{PM}$$
,

•
$$V_{GB} \approx V_{OX}^{acc}(V_{GB}) + \varphi_{PM}$$
.

•
$$V_{OX}^{acc}(V_{GB}) \approx V_{GB} - \varphi_{PM}$$
.

•
$$\mathcal{E}_{x,OX}^{acc}(V_{GB}) \approx \frac{V_{GB} - \varphi_{PM}}{X_{ox}}$$
.

•
$$Q_G^{acc}(V_{GB}) \approx C_{ox}(V_{GB} - \varphi_{PM})$$
.

•
$$Q_{SC,B}^{acc}(V_{GB}) \approx -C_{ox}(V_{GB} - V_{FB\cdot N})$$
.

The Flat-Band Voltage:

- $\bullet \ Q_{SC,B}(V_{FB\cdot N}) \equiv 0.$
- $\bullet \ V_{SCB}(V_{FB\cdot N}) \equiv 0.$
- $V_{FB\cdot N} = V_{OX}(V_{FB\cdot N}) + \varphi_{PM}$.
- $Q_G(V_{FB\cdot N}) = -\left(Q_f + Q_{it}(V_{FB\cdot N})\right)$.

•
$$\mathcal{E}_{x,OX}(V_{FB\cdot N}) = \frac{Q_G(V_{FB\cdot N})}{\epsilon_{ox}} = -\frac{\left(Q_f + Q_{it}(V_{FB\cdot N})\right)}{\epsilon_{ox}}$$
.

•
$$V_{OX}(V_{FB\cdot N}) = X_{ox} \mathcal{E}_{x,OX}(V_{FB\cdot N}) = -\frac{\left(Q_f + Q_{it}(V_{FB\cdot N})\right)}{C_{ox}}$$

•
$$V_{FB\cdot N} = \varphi_{PM} - \frac{\left(Q_f + Q_{it}(V_{FB\cdot N})\right)}{C_{ox}}$$
.

The Flat-Band Voltage:

- ullet The flat-band voltage $V_{FB:N}$ can be negative, zero, or positive.
- At the flat-band voltage:

$$n_B(x, V_{FB\cdot N}) = n_B^{\circ} = \frac{n_i^2}{N_{a,B}^-},$$

$$p_B(x, V_{FB \cdot N}) = p_B^{\circ} = N_{a,B}^{-},$$

$$\varrho_B(x, V_{FB\cdot N}) = \mathbf{0}\,,$$

and

$$\mathcal{E}_{x,B}(x,V_{FB\cdot N})=0.$$

The Depletion Bias Range:

$$\bullet \ V_{T\cdot N} \ge V_{GB} \ge V_{FB\cdot N} .$$

$$\bullet \ p_B^{\circ} \ge p_B(\mathbf{0}, V_{GB}) \ge n_B^{\circ}.$$

$$\bullet \ n_B^{\circ} \le n_B(\mathbf{0}, V_{GB}) \le p_B^{\circ}.$$

- $W_{d,B}^{dep}(V_{GB})$ increases from 0 to $W_{d,B}^{dep}(V_{T\cdot N})$.
- $V_{SC,B}^{dep}(V_{GB})$ increases from 0 to $2\,\varphi_{F,B}$.

In the approximate analysis:

•
$$W_{d,B}^{dep}(V_{GB}) \approx \sqrt{\frac{2 \epsilon_{Si}}{q N_{a,B}^-} V_{SC,B}^{dep}(V_{GB})}$$
.

•
$$Q_{SC,B}^{dep}(V_{GB}) \approx -\sqrt{2 q \epsilon_{Si} N_{a,B}^{-} V_{SC,B}^{dep}(V_{GB})}$$
.

The Depletion Bias Range:

•
$$Q_G^{dep}(V_{GB}) \approx \sqrt{2 q \epsilon_{Si} N_{a,B}^- V_{SC,B}^{dep}(V_{GB})} - \left[Q_f + Q_{it}^{dep}(V_{GB}) \right]$$
.

•
$$\mathcal{E}_{x,OX}^{dep}(V_{GB}) \approx \frac{\sqrt{2 q \epsilon_{Si} N_{a,B}^{-} V_{SC,B}^{dep}(V_{GB})}}{\epsilon_{ox}} - \frac{\left[Q_f + Q_{it}^{dep}(V_{GB})\right]}{\epsilon_{ox}}$$

•
$$V_{OX}^{dep}(V_{GB}) \approx \frac{\sqrt{2 q \epsilon_{Si} N_{a,B}^{-} V_{SC,B}^{dep}(V_{GB})}}{C_{ox}} - \frac{\left[Q_f + Q_{it}^{dep}(V_{GB})\right]}{C_{ox}}$$
.

•
$$V_{GB} \approx \frac{\sqrt{2 q \epsilon_{Si} N_{a,B}^{-} V_{SC,B}^{dep}(V_{GB})}}{C_{ox}} + V_{SC,B}^{dep}(V_{GB}) + V_{FB\cdot N}$$
.

The Depletion Bias Range:

•
$$V_{SC,B}^{dep}(V_{GB}) \approx V_{GB} - V_{FB\cdot N}$$

$$+ \frac{q \, \epsilon_{Si} \, N_{a,B}^{-}}{C_{ox}^{2}} \left[1 - \sqrt{1 + \frac{2 \, C_{ox}^{2}}{q \, \epsilon_{Si} \, N_{a,B}^{-}} \left(V_{GB} - V_{FB\cdot N} \right)} \right] .$$

• From this approximate relationship, we can calculate $V_{SC,B}^{dep}(V_{GB})$ for a certain value of V_{GB} . It is then possible to calculate all other MOS variables which depend only on $V_{SC,B}^{dep}(V_{GB})$.

The Threshold Voltage:

$$\bullet \ n_B(\mathbf{0}, V_{T:N}) = p_B^{\circ} \,,$$

$$\bullet \ p_B(\mathbf{0}, V_{T \cdot N}) = n_B^{\circ} \,,$$

•
$$V_{T\cdot N} = V_{OX}(V_{T\cdot N}) + V_{SC,B}(V_{T\cdot N}) + \varphi_{PM}$$
,

•
$$Q_G(V_{T\cdot N}) + Q_f + Q_{it}(V_{T\cdot N}) + Q_{SC,B}(V_{T\cdot N}) = 0$$
.

$$\bullet \ V_{SC\!,B}(V_{T\!\cdot\!N}) = \frac{2\,k_BT}{q} \ln\left(\frac{N_{a,B}^-}{n_i}\right) = 2\,\varphi_{F\!,B}\,, \label{eq:VSCB}$$

$$\bullet \ \varphi_{F,B} = \frac{k_B T}{q} \ln \left(\frac{N_{a,B}^-}{n_i} \right) \ .$$

The Threshold Voltage:

•
$$W_{d,B}(V_{T:N}) = \sqrt{\frac{2 \epsilon_{Si}}{q N_{a,B}^{-}} V_{SC,B}(V_{T:N})} = \sqrt{\frac{4 \epsilon_{Si} \varphi_{F,B}}{q N_{a,B}^{-}}}$$
.

•
$$Q_{SC,B}(V_{T:N}) = -q N_{a,B}^- W_{d,B}(V_{T:N}) = -\sqrt{4 q \epsilon_{Si} N_{a,B}^- \varphi_{F,B}}$$
.

•
$$Q_G(V_{T:N}) = \sqrt{4 q \epsilon_{Si} N_{a,B}^- \varphi_{F,B}} - [Q_f + Q_{it}(V_{T:N})].$$

•
$$\mathcal{E}_{x,OX}(V_{T:N}) = \frac{Q_G(V_{T:N})}{\epsilon_{ox}} = \frac{\sqrt{4 q \epsilon_{Si} N_{a,B}^- \varphi_{F,B} - \left[Q_f + Q_{it}(V_{T:N})\right]}}{\epsilon_{ox}}$$

•
$$V_{OX}(V_{T:N}) = \frac{\sqrt{4 q \epsilon_{Si} N_{a,B}^{-} \varphi_{F,B}}}{C_{ox}} - \frac{Q_f + Q_{it}(V_{T:N})}{C_{ox}}$$
.

The Threshold Voltage:

•
$$V_{T\cdot N} = V_{FB\cdot N} + 2\,\varphi_{F,B} + \frac{\sqrt{4\,q\,\epsilon_{Si}\,N_{a,B}^{-}\,\varphi_{F,B}}}{C_{ox}}$$
.

$$\bullet \quad \varphi_{PM} = - \ 0.51165 - \frac{k_BT}{q} \ln \left(\frac{N_{a,B}^-}{n_i} \right) \ .$$

The Inversion Bias Range:

•
$$V_{GB} \geq V_{T \cdot N}$$
,

$$\bullet \ n_B(\mathbf{0}, V_{GB}) \ge p_B^{\circ},$$

•
$$p_B(0, V_{GB}) \le n_B^{\circ}$$
.

In the approximate analysis:

•
$$Q_{SC,B}^{inv}(V_{GB}) = Q_{DEP,B}^{inv}(V_{GB}) + Q_{INV,B}^{inv}(V_{GB})$$
.

•
$$W_{d,B}^{inv}(V_{GB}) = W_{d,B}^{max} \approx W_{d,B}^{dep}(V_{T\cdot N}) \approx \sqrt{\frac{4 \epsilon_{Si} \varphi_{F,B}}{q N_{a,B}^{-}}}$$
.

•
$$V_{SC,B}^{inv}(V_{GB}) \approx V_{SC,B}^{inv}(V_{T\cdot N}) \approx 2\,\varphi_{F,B}$$
.

• The inversion-layer charge is assumed to be a charge sheet located at the gate-oxide/substrate interface.

The Inversion Bias Range:

•
$$Q_{DEP,B}^{inv}(V_{GB}) \approx -q N_{a,B}^{-} W_{d,B}^{max} \approx -\sqrt{4 q \epsilon_{Si} N_{a,B}^{-} \varphi_{F,B}}$$
.

•
$$Q_{INV,B}^{inv}(V_{GB}) \approx Q_{SC,B}^{inv}(V_{GB}) + \sqrt{4 q \epsilon_{Si} N_{a,B}^{-} \varphi_{F,B}}$$
.

•
$$V_{GB} \approx V_{OX}^{inv}(V_{GB}) + 2\varphi_{F,B} + \varphi_{PM}$$
.

•
$$V_{OX}^{inv}(V_{GB}) \approx V_{GB} - 2\varphi_{F,B} - \varphi_{PM}$$
.

•
$$\mathcal{E}_{x,OX}^{inv}(V_{GB}) \approx \frac{V_{GB} - 2\,\varphi_{F,B} - \varphi_{PM}}{X_{ox}}$$
.

•
$$Q_G^{inv}(V_{GB}) \approx C_{ox} \left(V_{GB} - 2 \varphi_{F,B} - \varphi_{PM} \right)$$
.

•
$$Q_{SC,B}^{inv}(V_{GB}) \approx -C_{ox} \left(V_{GB} - 2\varphi_{F,B} - V_{FB\cdot N}\right)$$
.

•
$$Q_{INV,B}^{inv}(V_{GB}) \approx -C_{ox}(V_{GB} - V_{T\cdot N})$$
.

SMALL-SIGNAL CAPACITANCE-VOLTAGE CHARACTERISTICS

•
$$C_{gb}(V_{GB}) = \frac{C_{ox} C_{sc,B}(V_{GB})}{C_{ox} + C_{sc,B}(V_{GB})}$$
.

- $C_{gb}^{acc}(V_{GB}) \approx C_{ox}$.
- $C_{sc,B}^{dep}(V_{GB}) \approx \frac{\epsilon_{Si}}{W_{d,B}^{dep}(V_{GB})} \approx \frac{\epsilon_{Si}}{\sqrt{2 \epsilon_{Si} V_{SC,B}^{dep}(V_{GB}) / q N_{a,B}^{-}}}$
- $W_{d,B}^{inv}(V_{GB}) = W_{d,B}^{dep}(V_{T\cdot N}) = W_{d,B}^{max} = \sqrt{\frac{4 \epsilon_{Si} \varphi_{F,B}}{q N_{a,B}^{-}}}$.

•
$$C_{sc,B\cdot HF}^{inv}(V_{GB}) = \frac{\epsilon_{Si}}{W_{d,B}^{max}} = \sqrt{\frac{q \,\epsilon_{Si} \,N_{a,B}^{-}}{4 \,\varphi_{F,B}}}$$
.

SMALL-SIGNAL CAPACITANCE-VOLTAGE CHARACTERISTICS

•
$$C_{gb\cdot HF}^{inv}(V_{GB}) = \frac{C_{ox} C_{sc,B\cdot HF}^{inv}(V_{GB})}{C_{ox} + C_{sc,B\cdot HF}^{inv}(V_{GB})} = \frac{1}{\left(\frac{X_{ox} + W_{d,B}^{max}}{\epsilon_{ox} + \epsilon_{Si}}\right)} \neq f(V_{GB}).$$

• $C_{gb \cdot LF}^{inv}(V_{GB}) \approx C_{ox}$.

MOSFET TYPES

- N-Channel and P-Channel MOSFETs
- Enhancement-Mode and Depletion-Mode MOSFETs
- Surface-channel and Buried-channel MOSFETs
- Bulk and Silicon-on-Insulator (SOI) MOSFETs

STATIC DRAIN-CURRENT CHARACTERISTICS

•
$$V_{T\cdot N}(V_{BS}) = V_{FB\cdot N0} + 2\varphi_{F,B} + \frac{1}{C_{ox}} \sqrt{2q\epsilon_{Si}N_{a,B}^{-}(2\varphi_{F,B} - V_{BS})}$$
.

•
$$V_{T\cdot N0} \equiv V_{T\cdot N}(V_{BS} = 0) = V_{FB\cdot N0} + 2\,\varphi_{F,B} + \gamma_{B\cdot N}\,\sqrt{2\,\varphi_{F,B}}$$
.

$$\bullet \ \gamma_{B\cdot N} \equiv \frac{\sqrt{2\,q\,\epsilon_{Si}\,N_{a,B}^{-}}}{C_{ox}} \,.$$

- $\bullet \ V_{DSat} = V_{GS} V_{T \cdot N}(V_{BS}).$
- $K_N = \mu_{n \cdot ch} C_{ox} \frac{W_{ch}}{L_{ch}}$.
- For $V_{GS} \leq V_{T \cdot N}(V_{BS})$, the NMOSFET is off and

$$I_D^{off} = 0$$
.

STATIC DRAIN-CURRENT CHARACTERISTICS

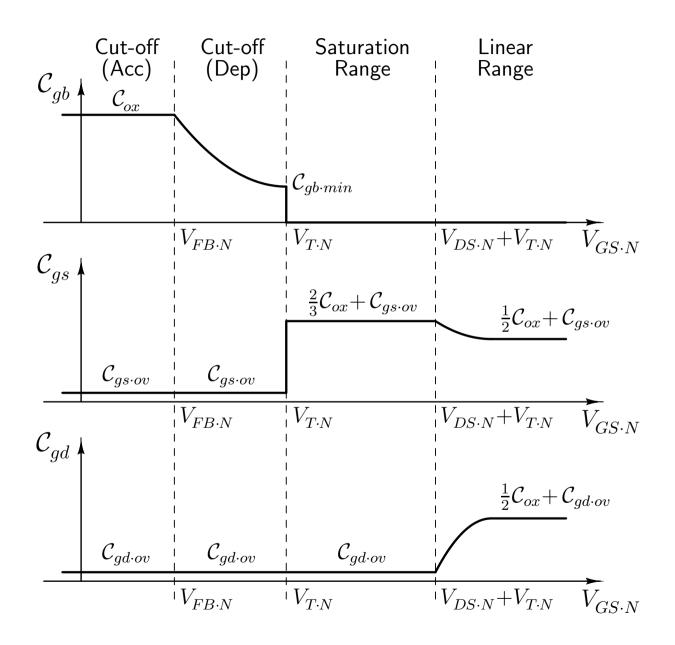
 \bullet For $V_{GS} \geq V_{T\cdot N}(V_{BS})$ and $V_{DS} \leq V_{DSat}$, the NMOSFET is in the linear bias range and

$$I_D^{lin} = K_N \left[\left(V_{GS} - V_{T \cdot N}(V_{BS}) \right) V_{DS} - \frac{1}{2} V_{DS}^2 \right].$$

 \bullet For $V_{GS} \geq V_{T\cdot N}(V_{BS})$ and $V_{DS} \geq V_{DSat}$, the NMOSFET is in the saturation bias range and

$$I_D^{sat} = \frac{K_N}{2} \left(V_{GS} - V_{T\cdot N}(V_{BS}) \right)^2 \left[1 + \lambda_N \left(V_{DS} - V_{DSat} \right) \right].$$

MOSFET CAPACITANCES



SMALL-SIGNAL MOSFET MODEL

•
$$i_d = g_m v_{gs} + g_{mb} v_{bs} + g_o v_{ds}$$
.

•
$$g_m^{sat} = K_N \left(V_{GS} - V_{T \cdot N}(V_{BS}) \right) \left[1 + \lambda_N \left(V_{DS} - V_{DSat} \right) \right].$$

$$\bullet \ g_{mb}^{sat} = \frac{\gamma_{B\cdot N}}{2\sqrt{2\,\varphi_{F,B} - V_{BS}}} g_m^{sat} \,.$$

•
$$g_o^{sat} = \frac{\lambda_N K_N}{2} \left(V_{GS} - V_{T \cdot N}(V_{BS}) \right)^2 = \frac{1}{r_o^{sat}},$$

•
$$f_T = \frac{g_m^{sat}}{2\pi \left(\mathcal{C}_{qs} + \mathcal{C}_{ad}\right)} = \frac{3\mu_{n\cdot ch}}{4\pi L_{ch}^2} \left(V_{GS} - V_{T\cdot N}(V_{BS})\right).$$